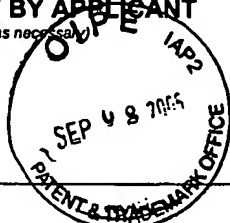


Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)



Complete if Known

Application Number	10/602,323
Filing Date	June 24, 2003
First Named Inventor	Ahn, Kie
Group Art Unit	2823
Examiner Name	Toledo, Fernando

Sheet 1 of 3

Attorney Docket No: 1303.101US1

US PATENT DOCUMENTS

Examiner Initial *	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Filing Date If Appropriate
<i>ht</i>	US-2002/0192975-A1	12/19/2002	Ahn, Kie Y.	06/17/2002
	US-2003/0045060-A1	03/06/2003	Ahn, Kie Y.	08/30/2001
	US-2003/0045078-A1	03/06/2003	Ahn, Kie Y., et al.	08/30/2004
	US-2003/0049942-A1	03/13/2003	Haukka, S., et al.	08/22/2002
	US-2003/0059535-A1	03/27/2003	Luo, L., et al.	09/25/2001
	US-2003/0104666-A1	06/05/2003	Bojarczuk, Jr., N. A., et al.	12/20/2002
	US-2003/0119246-A1	06/26/2003	Ahn, Kie Y.	12/20/2001
	US-2003/0119291-A1	06/26/2003	Ahn, Kie Y., et al.	12/20/2001
	US-2003/0132491-A1	07/17/2003	Ahn, Kie Y.	01/17/2002
	US-2003/0185980-A1	10/02/2003	Endo, K.	03/31/2003
	US-2004/0009679-A1	01/15/2004	Yeo, J., et al.	07/10/2003
	US-2004/0023461-A1	02/05/2004	Ahn, Kie Y., et al.	07/30/2002
	US-2004/0033661-A1	02/19/2004	Yeo, J., et al.	06/02/2003
	US-2004/0038554-A1	02/26/2004	Ahn, Kie Y.	08/21/2002
	US-2004/0043541-A1	03/04/2004	Ahn, Kie Y.	08/29/2002
	US-2004/0043569-A1	03/04/2004	Ahn, Kie Y.	08/28/2002
	US-2004/0043635-A1	03/04/2004	Vaartstra, B. A.	08/28/2002
	US-2004/0110348-A1	06/10/2004	Ahn, Kie Y., et al.	12/04/2002
	US-2004/0110391-A1	06/10/2004	Ahn, K. Y., et al.	12/04/2002
	US-2004/0164357-A1	08/26/2004	Ahn, Kie Y., et al.	02/27/2004
	US-2004/0164365-A1	08/26/2004	Ahn, Kie Y., et al.	02/27/2004
	US-2004/0168627-A1	09/02/2004	Conley, Jr., J. F., et al.	02/27/2003
	US-2004/0171280-A1	09/02/2004	Conley, Jr., J. F., et al.	02/27/2003
	US-2004/0175882-A1	09/09/2004	Ahn, Kie Y., et al.	03/04/2003
	US-2004/0183108-A1	09/23/2004	Ahn, Kie Y.	01/27/2004
	US-2004/0185654-A1	09/23/2004	Ahn, Kie Y.	01/30/2004
	US-2004/0203254-A1	10/14/2004	Conley, Jr., J. F., et al.	04/11/2003
	US-2004/0235313-A1	11/25/2004	Frank, M. M., et al.	06/24/2004
	US-2004/0266217-A1	12/30/2004	Kim, K., et al.	06/23/2004
	US-2005/0009370-A1	01/13/2005	Ahn, Kie Y.	08/04/2004
	US-2005/0023574-A1	02/03/2005	Forbes, L., et al.	09/02/2004
	US-2005/0026458-A1	02/03/2005	Basceri, C., et al.	08/26/2004
	US-2005/0030825-A1	02/10/2005	Ahn, K. Y.	08/31/2004
	US-2005/0037563-A1	02/17/2005	Ahn, Kie Y.	08/31/2004
	US-2005/0054165-A1	03/10/2005	Ahn, K. Y., et al.	03/31/2003
	US-2005/0077519-A1	04/14/2005	Ahn, Kie, et al.	10/10/2003
	US-2005/0124174-A1	06/09/2005	Ahn, K. Y., et al.	01/07/2005
	US-2005/0145957-A1	07/07/2005	Ahn, K. Y., et al.	02/16/2005
	US-2005/0158973-A1	07/21/2005	Ahn, K. Y., et al.	01/14/2005
<i>ht</i>	US-2005/0164521-A1	07/28/2005	Ahn, Kie Y., et al.	03/21/2005

EXAMINER

DATE CONSIDERED

11/23/05

Substitute for form 1449A/PTO
**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**
(Use as many sheets as necessary)

Complete if Known

Application Number	10/602,323
Filing Date	June 24, 2003
First Named Inventor	Ahn, Kie
Group Art Unit	2823
Examiner Name	Toledo, Fernando

Sheet 2 of 3

Attorney Docket No: 1303.101US1

US PATENT DOCUMENTS

Examiner Initial *	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Filing Date If Appropriate
<i>HL</i>	US-6,509,280	01/21/2003	Choi, Sung-Je	02/13/2002
	US-6,541,079	04/01/2003	Bojarczuk, Jr., N. A., et al.	10/25/1999
	US-6,551,929	04/22/2003	Kori, M., et al.	06/28/2000
	US-6,592,942	07/15/2003	Van Wijck, M. A.	07/07/2000
	US-6,638,859	10/28/2003	Sneh, O., et al.	09/27/2002
	US-6,652,924	11/25/2003	Sherman, A.	05/24/2001
	US-6,686,212	02/03/2004	Conley, Jr., J. F., et al.	10/31/2002
	US-6,709,989	03/23/2004	Ramdani, J., et al.	06/21/2001
	US-6,770,536	08/03/2004	Wilk, G. D., et al.	10/03/2002
	US-6,777,353	08/17/2004	Putkonen, M.	04/08/2003
	US-6,787,370	09/07/2004	Forbes, Leonard	12/16/2002
	US-6,787,413	09/07/2004	Ahn, Kie Y.	06/17/2002
	US-6,790,791	09/14/2004	Ahn, Kie Y., et al.	08/15/2002
	US-6,800,567	10/05/2004	Cho, H. J.	08/22/2002
	US-6,803,311	10/12/2004	Choi, E.	12/27/2002
	US-6,812,100	11/02/2004	Ahn, K. Y., et al.	03/13/2002
	US-6,844,260	01/18/2005	Sarigiannis, D., et al.	01/30/2003
	US-6,858,444	02/22/2005	Ahn, K. Y., et al.	06/20/2003
	US-6,884,739	04/26/2005	Ahn, K. Y., et al.	08/15/2002
	US-6,893,984	05/17/2005	Ahn, K. Y., et al.	02/20/2002
	US-6,900,122	05/31/2005	Ahn, K. Y., et al.	12/20/2001
	US-6,914,800	07/05/2005	Ahn, K. Y., et al.	08/31/2004
<i>HL</i>	US-6,921,702	07/26/2005	Ahn, K. Y., et al.	07/30/2002
	US-6,930,346	08/16/2005	Ahn, K. Y., et al.	08/31/2004

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	T ²
--------------------	---------------------	------------------	---	----------------

OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ³
<i>HL</i>		AHN, KIE Y., et al., "ALD OF AMORPHOUS LANTHANIDE DOPED TIOX FILMS", U.S. Application Serial No. 11/092,072; filed March 29, 2005	
<i>HL</i>		AHN, KIE Y., et al., "ATOMIC LAYER DEPOSITED HAFNIUM TANTALUM OXIDE DIELECTRICS", U.S. Application Serial No. 11/029,757; filed January 5, 2005	
<i>HL</i>		AHN, KIE Y., et al., "ATOMIC LAYER DEPOSITED LANTHANUM ALUMINUM OXIDE DIELECTRIC LAYER", U.S. Application Serial No. 10/930,167; filed August 31, 2004	

EXAMINER *F. Toledo*

DATE CONSIDERED *11/23/05*

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMG control number.

Substitute for form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	10/602,323
Filing Date	June 24, 2003
First Named Inventor	Ahn, Kie
Group Art Unit	2823
Examiner Name	Toledo, Fernando

Sheet 3 of 3

Attorney Docket No: 1303.101US1

OTHER DOCUMENTS – NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<i>ht</i>		AHN, KIE Y., et al., "ATOMIC LAYER DEPOSITED LANTHANUM HAFNIUM OXIDE DIELECTRICS", U.S. Application Serial No. 11/010,529; filed December 13, 2004	
		AHN, KIE Y., et al., "ATOMIC LAYER DEPOSITED TITANIUM ALUMINUM OXIDE FILMS", U.S. Application Serial No. 10/931,533; filed August 31, 2004	
		AHN, KIE Y., et al., "ATOMIC LAYER DEPOSITION OF Hf3N4/HfO2 FILMS AS GATE DIELECTRICS", U.S. Application Serial No. 11/063,717; filed February 23, 2005	
		AHN, KIE Y., et al., "ATOMIC LAYER DEPOSITION OF ZIRCONIUM-DOPED TANTALUM OXIDE FILMS", U.S. Application Serial No. 10/909,959; filed August 2, 2004	
		AHN, KIE Y., et al., "ATOMIC LAYER DEPOSITION OF Zr3N4/ZrO2 FILMS AS GATE DIELECTRICS", U.S. Application Serial No. 11/058,563; filed February 15, 2005	
		AHN, KIE Y., et al., "HYBRID ALD-CVD OF PrXOY/ZrO2 FILMS AS GATE DIELECTRICS", U.S. Application Serial No. 11/010,766; filed December 13, 2004	
		AHN, KIE Y., et al., "RUTHENIUM GATE FOR A LANTHANIDE OXIDE DIELECTRIC LAYER", U.S. Application Serial No. 10/926,812; filed August 26, 2004	
<i>ht</i>		WILK, G. D., et al., "High-K gate dielectrics: Current status and materials properties considerations", Journal of Applied Physics, 89(10), (May 2001), 5243-5275	

EXAMINER

DATE CONSIDERED

11/23/05

Substitute Disclosure Statement Form (PTO-1449)

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 608. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. Applicant's unique citation designation number (optional) * Applicant is to place a check mark here if English language Translation is attached